



**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No.: 10/712,775                      Group Art Unit: 1765  
Filing Date: November 14, 2003              Examiner: Alanko, Anita Karen  
Applicant: Donggyun HAN et al.  
Title: APPARATUS AND METHOD FOR REMOVING  
PHOTORESIST FROM A SUBSTRATE  
Attorney Docket: 2557-000216/US

Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314  
**Mail Stop Amendment**

Date: October 24, 2007

**AMENDMENT UNDER 35 U.S.C. §1.114**

Sir:

In response to the Office Action mailed August 24, 2007, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

**Amendments to the Claims** begin on page 2 of this Amendment.

**Remarks** begin on page 8 of this Amendment.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
<b>Total</b>	36	-	50	=	0
<b>Independent</b>	3	-	4	=	0